



Imale

843.41042X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): K. Hayano, et al.

Application No.: 10/025,457

Filing Date: December 26, 2001

For: METHOD OF MANUFACTURING PHOTOMASK AND METHOD OF
MANUFACTURING SEMICONDUCTOR INTEGRATED CIRCUIT
DEVICE

Art Unit: 1756

Examiner: S. Mohamedulla

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 30, 2004

Sir:

In response to the Office Action mailed December 31, 2003, please amend the
above-identified application as listed in the following, and as set forth on the following
pages:

Amendments to the Claims; and

Remarks are included following the amendments.